## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Eric Bornstein

Application Serial No.: 10/649,910
Filing Date: 08/26/2003

Title: NEAR INFRARED MICROBIAL ELIMINATION LASER

SYSTEM

Examiner: Shay, David M.

Art Unit: 3735

Atty. Docket No.: 093991-0019 (formerly 072287-0019)

Confirmation No.: 5770

## SUBMITTED VIA EFS-WEB

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

## AMENDMENT AND REPLY

This paper is in response to the non-final Office Action dated 03/19/2008 for the aboveidentified application. The Applicant appreciates the Examiner's thorough examination of the subject application, and requests reconsideration and further examination be in light of the following amendments and arguments.

Please amend the application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper; and

Remarks begin on page 4 of this paper.